

강소기업뉴스 (Korea)

EV Group brings high-speed high-precision metrology to 3D heterogeneous integration - November 17, 2021

EVG unveiled the EVG®40 NT2 automated metrology system, which provides overlay and CD measurements for W2W, D2W and D2D bonding as well as maskless lithography applications. The EVG40 NT2 system provides highly precise measurements of critical bonding and lithography process parameters for current and future leading-edge 3D/heterogeneous integration applications. These measurements include: alignment verification and monitoring for W2W, D2W, D2D and maskless exposure processes; CD measurement; and multi-layer thickness measurement. It is a highly scalable system that features multiple measurement heads and a high-precision stage designed for high-throughput and high-accuracy (down to the low single-digit nm range) bonding and maskless exposure alignment verification.

<http://www.kdpress.co.kr/news/articleView.html?idxno=108393>